



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Florence Eschbach et al. Art

Art Unit: 1773

Serial No.: 10/649,354

Examiner: Vivian Chen

Filed

: August 26, 2003

Assignee

: Intel Corporation

Title

: ATTACHING A PELLICLE FRAME TO A RETICLE

Mail Stop Amendment

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Dear Sir:

Applicants call attention to the attached Information
Disclosure Statement and documents listed on form PTO-1449.

Each enclosed document listed on the herewith Form PTO-1449 was cited in the attached International Search Report dated August 25, 2005, issued in a foreign counterpart application not more than three months ago. To the best knowledge of the undersigned, this is the first citation of these items in any communication from a foreign patent office in a counterpart foreign application. No fee is required.

CERTIFICATE OF MAILING BY FIRST CLASS MAIL

I hereby certify under 37 CFR §1.8(a) that this correspondence is being deposited with the United States Postal Service as first class mail with sufficient postage on the date indicated below and is addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

October 12

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Jennifer H. Payne

Typed or Printed Name of Person Signing Certificate

Applicant: Florence Eschbach et al. Attorney's Docket No.: 10559-887001 / P17697

Serial No.: 10/649,354 Filed: August 26, 2003

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The documents are in the English language; hence no concise explanation is necessary per Rule 98(a)(3).

Consideration of the foregoing and enclosures plus the return of a copy of the enclosed form PTO-1449 with the Examiner's initials in the left column per MPEP 609 are earnestly solicited along with an early action on the merits.

Please apply any additional charges or credits to Deposit Account No. 06-1050.

Date: October 12, 2005

Respectfully submitted,

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Sheet	1	of	1	

01	PSydstitute Form PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 10559-887001	Application No. 10/649,354
	OCT 1 4 2005 Information Disclosure Statemen		Applicant Florence Eschbach et a	ıl.
PATTERY & A.A.	(Use several sh	eets if necessary)	Filing Date August 26, 2003	Group Art Unit 1773

U.S. Patent Documents							
Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH			-			
	AI						

Foreign Patent Documents or Published Foreign Patent Applications								
Examiner	Desig.	Document	Publication	Country or			Trans	slation
Initial	ID	Number	Date	Patent Office	Class	Subclass	Yes	No
	AJ	0 942 325	09/1999	EPO				
	AK							
	AL							
	AM							
	AN							

	Other Documents (include Author, Title, Date, and Place of Publication)				
Examiner	Desig.				
Initial	ID	Document			
	AO	Chen, et al., "Pellicle-Induced Reticle Distortion: An Experimental Investigation", Proc. of SPIE - The Int'l Soc. for Optical Engineering, Vol. 3546, pp. 167-172 (1998).			
	AP	Cotte, et al., "Effects of Soft Pellicle Frame Curvature and Mounting Process on Pellicle-Induced Distortions in Advanced Photomasks", <i>Proc. of SPIE - The Int'l Soc. for Optical Engineering</i> , Vol. 5040, pp. 1044-1054 (2003).			
	AQ	Cotte, et al., "Experimental and Numerical Studies of the Effects of Materials and Attachment Conditions on Pellicle-Induced Distortions in Advanced Photomasks", <i>Proc. of SPIE - The Int'l Soc. for Optical Engineering</i> , Vol. 4754, pp. 579-588 (2002).			
	AR	Cotte, et al., "Numerical and Experimental Studies of Pellicle-Induced Photomask Distortions", Proc. of SPIE - The Int'l Soc. for Optical Engineering, Vol. 4562, pp. 641-651 (2002).			

Examiner Signature	Date Considered
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